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Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>		Complete if Known	
Sheet	1	of	1
Application Number		T.B.A.	
Filing Date		Even Date Herewith	
First Named Inventor		Wolfgang M.J. Hofmann	
Group Art Unit		1772	
Examiner Name		Hofmann	
Attorney Docket Number		Hofmann	

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
PCD		5,198,390		MacDonald	03/03/1993	
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PCD		5,235,187		Arney	08/10/1993	
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Examiner Initials*	Cite No. ¹	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ²
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Examiner Signature		Date Considered	12/10/2005
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Sheet	1	of	1	Attorney Docket Number	Hofmann

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Examiner Signature	<i>John H. Charles, III</i>	Date Considered	12/10/2005
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Sheet 1	of 1	Attorney Docket Number	Hofmann

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
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MD		CHANG, T.H.P.; Kern, D.P., Muray, L.P.; Microminiaturization of electron optical systems; J. Vacuum Science & Technology B, vol. 8, pp. 1698-1705, 1990	
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Examiner Signature	<i>Deborah Harris</i>	Date Considered	12/10/2005
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Sheet 1	of 1	Attorney Docket Number	Hofmann

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Examiner Signature	<i>Deborah L. Davis</i>	Date Considered	12/10/2005
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Examiner Signature	<i>Joseph Chaboun</i>	Date Considered	12/10/2005
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